

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L11	1531	resonator\$2 and bias\$5 and sputter\$5	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 14:34
L12	583	resonator\$2 and bias\$5 and sputter\$5 and (ions or ionized)	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 14:48
L13	959	resonator\$2 and (bias\$5 same (substrate or workpiece or resonator\$2)) and sputter\$5	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 14:50
L14	661	resonator\$2 and (bias\$5 same (substrate or workpiece or resonator\$2)) and sputter\$5 and (bias\$5 same (layer\$2 or deposit\$2))	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 15:42
L15	5	("6262637" "6377137" "6483229" "6486751" "6566979").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 15:03
L16	5	resonator\$2 and bias\$5 and sputter\$5	EPO; JPO; DERWENT	OR	OFF	2007/07/11 15:39
L17	9	piezoelectric\$5 and bias\$5 and sputter\$5	EPO; JPO; DERWENT	OR	OFF	2007/07/11 15:42
L18	642	piezoelectric\$2 and (bias\$5 same (substrate or workpiece or resonator\$2)) and sputter\$5 and (bias\$5 same (layer\$2 or deposit\$2))	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 15:43
L19	734	(MEMS or (micro adj electromechanical or electromechanical)) and (bias\$5 same (substrate or workpiece or resonator\$2)) and sputter\$5 and (bias\$5 same (layer\$2 or deposit\$2))	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 15:46
L20	273	(MEMS or (micro adj electromechanical or electromechanical)) and (bias\$5 adj5 (substrate or workpiece)) and sputter\$5 and (bias\$5 same (layer\$2 or deposit\$2))	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:15
L21	710	(bias\$5 adj5 (areas or regions or sections)) and sputter\$5	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 15:50
L22	465	(bias\$5 adj5 (areas or regions or sections)) and sputter\$5 and (bias\$5 same (substrate or workpiece))	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 16:08
L23	11	(bias\$5 adj5 (areas or regions or sections)) and sputter\$5	EPO; JPO; DERWENT	OR	OFF	2007/07/11 15:56
L24	39	(bias\$5 adj5 (area\$3 or region\$3 or section\$3)) and sputter\$5	EPO; JPO; DERWENT	OR	OFF	2007/07/11 15:56

## EAST Search History

L26	1128	(bias\$5 adj5 (area\$2 or region\$2 or section\$2)) and sputter\$5 and (bias\$5 same (substrate or workpiece)) and ((substrate or workpiece) same (area\$2 or region\$2 or section\$2))	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 16:10
L27	106	(bias\$5 adj5 (area\$2 or region\$2 or section\$2)) and sputter\$5 and (bias\$5 same (substrate or workpiece)) and ((substrate or workpiece) same (area\$2 or region\$2 or section\$2)) and (mems or microelectromechanical or (micro adj electromechanical) or resonator\$2)	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 16:18
L28	39	(bias\$5 adj5 (area\$2 or region\$2 or section\$2)) and sputter\$5	EPO; JPO; DERWENT	OR	OFF	2007/07/11 16:19
L29	145	(bias\$5 adj5 ((area\$2 or region\$2 or section\$2) adj10 (substrate\$5 or workpiece))) and sputter\$5	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 16:34
L30	7	("4569743").URPN.	USPAT	OR	OFF	2007/07/11 16:31
L31	6	("3321390"   "3707452"   "3986944"   "4013830").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 16:32
L32	904	(bias\$5 same (substrate\$5 or workpiece)) and sputter\$5	EPO; JPO	OR	OFF	2007/07/11 16:35
L33	166	(bias\$5 same (substrate\$5 or workpiece)) and sputter\$5 and (region\$5 or area\$3 or location\$3 or section\$3)	EPO; JPO	OR	OFF	2007/07/11 16:44
L34	89	204/298.15.ccls.	EPO; JPO	OR	OFF	2007/07/11 16:44
L35	400	204/298.15.ccls.	USPAT; USOCR	OR	OFF	2007/07/11 16:44
L36	21	("3730873"   "4222838"   "4349409"   "4392938"   "4535835"   "4632719"   "4692727"   "4853102"   "4871420"   "4950377"   "4968374"   "4983253"   "5014217"   "5091208"   "5203981"   "5213658"   "5228940"   "5246532"   "5271788"   "5298720").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:10
L37	37	204/298.16.ccls. and barnes	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:10
L38	1	"5178739".pn.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:10
L39	12580	(MEMS or (micro adj electromechanical or electromechanical) or resonator\$5) and sputter\$5	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:18

## EAST Search History

L40	7831	(MEMS or (micro adj electromechanical or electromechanical) or resonator\$5) and sputter\$5 and frequency	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:18
L41	4311	(MEMS or (micro adj electromechanical or electromechanical) or resonator\$5) and sputter\$5 and frequency and filter\$2	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:18
L42	697	(MEMS or (micro adj electromechanical or electromechanical) or resonator\$5) and sputter\$5 and frequency and filter\$2 and ("204"/\$.ccls. or "427"/\$.ccls. or "438"/\$.ccls.)	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:21
L43	280	(MEMS or (micro adj electromechanical or electromechanical) or resonator\$5) and sputter\$5 and frequency and filter\$2 and ("204"/\$.ccls. or "427"/\$.ccls. or "438"/\$.ccls.) and bias\$5	US-PGPUB; USPAT; USOCR	OR	OFF	2007/07/11 17:48
L46	0	(MEMS or (micro adj electromechanical or electromechanical) or resonator\$5) and sputter\$5 and filter\$2 and bias\$5	EPO; JPO	OR	OFF	2007/07/11 17:50
L47	2	(MEMS or (micro adj electromechanical or electromechanical) or resonator\$5) and sputter\$5 and bias\$5	EPO; JPO	OR	OFF	2007/07/11 17:50